

Course Schedule, room IOF RAN

MONDAY

11:05 — 11:50	■ LEC Methods Of Laser Technology Design (2018-02-05 — 2018-03-12) 🧑‍🎓 M16-214 🎓 Garanin S.G., Vovchenko E.D.
11:55 — 12:40	■ LEC Ultrashort Laser Pulses (2018-02-05 — 2018-04-09) 🧑‍🎓 M16-214 🎓 Garanin S.G., Skvortsova N.N.
12:45 — 14:20	■ SEM Ultrashort Laser Pulses (2018-02-05 — 2018-04-09) 🧑‍🎓 M16-214 🎓 Garanin S.G.
14:30 — 16:05	■ SEM Methods Of Laser Technology Design (2018-02-05 — 2018-04-09) 🧑‍🎓 M16-214 🎓 Bukin V.V., Garanin S.G.

TUESDAY

08:30 — 10:05	☑ LAB Plasma Physics and Plasma Devices (2018-02-06 — 2018-04-17) 🧑‍🎓 B14-202 🎓 Tsvetkov V.B., Skvortsova N.N.
10:15 — 11:00	■ LEC Plasma Physics and Plasma Devices (2018-02-06 — 2018-04-17) 🧑‍🎓 B14-202 🎓 Garnov S.V., Skvortsova N.N.
10:15 — 12:40	■ SEM Methods and Techniques of Laser Physics Experiments 🧑‍🎓 B15-202 🎓 Vovchenko E.D., Gerasimov I.A.
11:55 — 15:15	■ SEM Plasma Physics and Plasma Devices (2018-02-06 — 2018-04-17) 🧑‍🎓 B14-202 🎓 Tsvetkov V.B., Skvortsova N.N.
12:45 — 13:30	■ LEC Methods and Techniques of Laser Physics Experiments 🧑‍🎓 B15-202 🎓 Gerasimov I.A., Vovchenko E.D.
15:20 — 17:00	☑ LEC Ultrashort-pulse Lasers. (2018-02-06 — 2018-04-17) 🧑‍🎓 B14-202 🎓 Garnov S.V., Shafeev G.A. ☑ SEM Ultrashort-pulse Lasers. (2018-02-13 — 2018-04-10) 🧑‍🎓 B14-202 🎓 Tsvetkov V.B., Garnov S.V.

THURSDAY

10:15 — 11:50	■ SEM Professional Practice (Pre-graduation) (2018-02-08 — 2018-04-12) 🧑‍🎓 M16-214 🎓 Garnov S.V., Ananin O.B.
12:45 — 14:20	■ SEM Academic (Research) Practice: Laser Systems Radiation-Matter Interaction (2018-02-08 — 2018-04-12) 🧑‍🎓 M16-214 🎓 Garnov S.V., Ananin O.B.
14:30 — 17:00	■ SEM Workshop in Laser Physics (2018-02-08 — 2018-04-12) 🧑‍🎓 M16-214 🎓 Gerasimov I.A., Bukin V.V.

FRIDAY

10:15 — 12:40	■ PR Professional Internship 🧑‍🎓 M17-214 🎓 Gerasimov I.A., Garnov S.V.
12:45 — 14:20	☑ LEC Laser Optics (Part II) (2018-02-09 — 2018-04-20) 🧑‍🎓 B14-202 🎓 Gerasimov I.A., Vovchenko E.D. ☑ SEM Laser Optics (Part II) (2018-02-16 — 2018-04-13) 🧑‍🎓 B14-202 🎓 Gerasimov I.A., Vovchenko E.D.